Equipment list Kavli Nanolab Version 16

code	name	type	owner	back-up	risk
	Lithography				
L1	EBPG-5000+	Vistec EBPG5000+	A. v Run	A. v Langen	LOW
L1a	EBPG-5200	Vistec EBPG5200	A. v Run	A. v Langen	LOW
L2	NUV	EVG 620	B. v.d. Bulk	E. Straver	LOW
L4	Laserwriter-1	Heidelberg	A. v Langen	C. de Boer	LOW
L11	spinner 1		E. Straver	B. v.d. Bulk	LOW
L12	spinner 2		E. Straver	B. v.d. Bulk	LOW
L13	Laminator	Dyna Tex DXM-123-02	B. v.d. Bulk	E. Straver	LOW
L14	mask spinner	Karl Suss CT60	A. v Langen	E. Straver	LOW
L15	Wafer track	Suss Delta 80	E. Straver	B. v.d. Bulk	MEDIUM
L16	hotplate 1		E. Straver	B. v.d. Bulk	LOW
L17	hot plate 2		E. Straver	B. v.d. Bulk	LOW
L18	hot plate 3		E. Straver	B. v.d. Bulk	LOW
L19	spinner 3		E. Straver	B. v.d. Bulk	LOW
	Inspection				
I1	Optical microscope 4	Olympus BX53	L. Schriek	E. Straver	LOW
I2	SEM Hitachi	Hitachi S4800	H. Miro	R. v.d. Kolk	LOW
I3	Aligment microscope 2	Leica Ergolux	A. v Run	A. v Langen	LOW
I4	SEM Nova Nano	FEI Nova Nano	H. Miro	R. v.d. Kolk	LOW
I6	Helios FIB/SEM	FEI Helios CX	H. Miro	D. Lauer	LOW
I7	Optical microscope 1	Olympus BX5	L. Schriek	E. Straver	LOW
I8	Optical microscope 2	Olympus BX51	L. Schriek	E. Straver	LOW
I9	Optical microscope 3	Olympus BX51	L. Schriek	E. Straver	LOW
I10	Alignment microscope 1	Leica Ergolux	A. v Run	A. v Langen	LOW
I11	Leitz 1	Leica Ergolux	L. Schriek	E. Straver	LOW
I12	Leitz 2 (IR cam)	Leica Ergolux	L. Schriek	E. Straver	LOW
I13	Leitz 3	Leica Ergolux	L. Schriek	E. Straver	LOW
I14	3D microscope	Keyence	L. Schriek	E. Straver	LOW
I16	Particle counter	Spotifix	L. Schriek	B. v.d. Bulk	LOW
I17	Microscope	Zeiss	Chung-Kai Yang	Z. Heidarnia	LOW
I18	SEM Hitachi	Regulas8230	H. Miro	R. v.d. Kolk	LOW
I19	Optical microscope	Leica INM20	L. Schriek	E. Straver	LOW
I20	Lift-Off microscope	DinoLite	L. Schriek	E. Straver	LOW
I21	Optical Microscope 5	Olympus BX53	L. Schriek	C. de Boer	LOW
I22	Contour 500	Bruker WLI interferometer	L. Schriek	R. v.d. Kolk	LOW
	Ovens				
O1	Furnace oxidation	Tempress A2	R. v.d. Kolk	C. de Boer	HIGH
O2	Furnace anneal	Tempress A3	R. v.d. Kolk	C. de Boer	HIGH
O3	Furnace LPCVD	Tempress A4	R. v.d. Kolk	C. de Boer	HIGH
O4	RTP	SSI - Solaris 100	R. v.d. Kolk	C. de Boer	HIGH
O5	Vacuum oven	Thermo Hereaus	E. Straver	B. v.d. Bulk	LOW
O8	Vacuum oven 2	Binder	E. Straver	B. v.d. Bulk	LOW
O9	Drying Oven Top	Venticell	B. v.d. Bulk	E. Straver	LOW
O10	Vacuum oven	Binder	E. Straver	B. v.d. Bulk	LOW
O11	Dry oven	glassware	E. Straver	B. v.d. Bulk	LOW
O13	Vacuum anneal oven	Diamond films	E. Straver	B. v.d. Bulk	MEDIUM
O14	Drying Oven Bottom	Venticell	B. v.d. Bulk	E. Straver	LOW
	PVD				

P1	Leybold	Leybold Heraeus LH560	M. Fischer	B. van Asten	LOW
P2	Temescal	Temescal FC-2000	B. van Asten	M. Fischer	LOW
P3	AC-dielectric	Alliance AC450	M. Fischer	B. van Asten	LOW
P4	AC-Metal1	Alliance AC450	M. Fischer	B. van Asten	LOW
P5	SEM sputter coater	Leica	H. Miro	M. vd Krogt	LOW
P6	AC-Metal2	Alliance AC450	M. Fischer	B. van Asten	LOW
P7	AC-EVA 450	Alliance EVA450	B. van Asten	M. Fischer	LOW
P8	QT-AJA	AJA int.	M. Fischer	B. van Asten	LOW
P9	Plassys	MEB550S2	B. van Asten	M. Fischer	LOW
P10	MB-AJA	AJA Int.	M. Fischer	B. van Asten	LOW
P11	Super-AJA	AJA int.	M. Fischer	B. van Asten	LOW
	CVD				
C1	ALD Oxford	Oxford Instr. Flexal	B. van Asten	M. Fischer	LOW
C2	Oxford PECVD	Plasmalab 80plus	R. v.d. Kolk	M. Fischer	MEDIUM
C3	CNT/ First Nano	First Nano Easy Tube 2000	R. v.d. Kolk	C. de Boer	MEDIUM
C4	ALD Veeco	Veeco Fiji G2	B. van Asten	M. Fischer	LOW
C5	Diamond CVD	SEKI SDS6300	T. Yamamoto	R. v.d. Kolk	MEDIUM
C6	ALD Picosun	Picosun R200	S. Amitonov	_	LOW
C7	ALD Anric	AT410	B. van Asten	M. Fischer	LOW
C8	ICP PE-CVD	Oxford Instr. Flexal	R. v.d. Kolk	C. de Boer	MEDIUM
C9	ALD Picosun 2		M. Aghaee	B. van Asten	LOW
	Measurement				
M1	Ellipsometer	Woollam	L. Schriek	R. v.d. Kolk	LOW
M2	Stressmeter	Flexus (TOHO)	L. Schriek	R. v.d. Kolk	LOW
M3	4-point probe	Lucas Labs	L. Schriek	R. v.d. Kolk	LOW
M4	AFM	Bruker Fast Scan	L. Schriek	R. v.d. Kolk	LOW
M5	Raman	Renishaw	L. Schriek	R. v.d. Kolk	LOW
M6	Profiler Bruker 1	Bruker Dektak XT motorized	L. Schriek	R. v.d. Kolk	LOW
M7	Profiler Bruker 2	Bruker Dektak XT manual	L. Schriek	R. v.d. Kolk	LOW
M8	Probe Station	SPS 1000	L. Schriek	R. v.d. Kolk	LOW
M9	FR portable	ThetaMetris	L. Schriek	R. v.d. Kolk	LOW
M10	particle counter	CVS	L. Schriek	B. v.d. Bulk	LOW
M11	XRD	Bruker XRD	H. Miro	H. Miro	MEDIUM
	Dry etching				
E1	Oxford Estrelas DSE	Plasma Pro 100	C. de Boer	R. v.d. Kolk	LOW
E2	AMS-Bosch	Adixen ICP-100	C. de Boer	R. v.d. Kolk	LOW
E3	AMS100 Cryo	Adixen ICP-100	C. de Boer	R. v.d. Kolk	LOW
E5	Sentech RIE F1	Etchlab200	C. de Boer	R. v.d. Kolk	LOW
E6	Sentech RIE F2	Etchlab200	C. de Boer	R. v.d. Kolk	LOW
E7	TePla-1	TePla 300 Plasma asher	C. de Boer	R. v.d. Kolk	LOW
E8	Oxford CI ICP	PlasmaLab100	C. de Boer	R. v.d. Kolk	LOW
E9	Oxford CI Cobra III-V	PlasmaPro 100 Cobra	C. de Boer	R. v.d. Kolk	LOW
E10	SCIA Ion Beam Etcher	scia Mill 150	C. de Boer	R. v.d. Kolk	LOW
E11	Tepla-2	GIGAbatch Plasma Etcher	C. de Boer	R. v.d. Kolk	LOW
E12	Sample cleaner ZONE II	Hitachi	H. Miro	_	LOW
	Wet chemistry				
W1	CPD-Right	Leica	E. Straver	B. v.d. Bulk	MEDIUM
W3	HF-VE	Idonus	E. Straver	B. v.d. Bulk	HIGH
W5	KOH etch-Left	-	E. Straver	B. v.d. Bulk	MEDIUM
W6	CPD-left	Tousimis	E. Straver	B. v.d. Bulk	MEDIUM

W7	KOH etch-Right	-	E. Straver	B. v.d. Bulk	MEDIUM
W8	Au plating	Autolab	E. Straver	B. v.d. Bulk	MEDIUM
W9	Wet Bench A	-	E. Straver	B. v.d. Bulk	HIGH
W10	Wet Bench B	-	E. Straver	B. v.d. Bulk	HIGH
W11	Wet Bench C	-	E. Straver	B. v.d. Bulk	HIGH
W13	Vaccuum Desiccator 1	Ted Pella Pelco	E. Straver	B. v.d. Bulk	LOW
W14	Vaccuum Desiccator 2	Ted Pella Pelco	E. Straver	B. v.d. Bulk	LOW
W15	Ultrasone bath 1	_	E. Straver	B. v.d. Bulk	LOW
W16	Ultrasone bath 2	_	E. Straver	B. v.d. Bulk	LOW
W17	Ultrasone bath 3	_	E. Straver	B. v.d. Bulk	LOW
W18	Vaccuum Desiccator 3	_	E. Straver	B. v.d. Bulk	LOW
	Misceleneous				
V1	Wafer dicer Disco	DAD3320	A. v Langen	C. de Boer	LOW
V2	Wafer bonder	EVG 501	R. v.d. Kolk	B. van Asten	MEDIUM
V3	Wire bonder	Westbond 454647E	L. Schriek	R. v.d. Kolk	LOW
V4	Breaking tool	Lattice Gear	B. v.d. Bulk	E. Straver	LOW
V5	Sample Cleaner	Zone-II	H. Miro	L. Schriek	LOW
V6	Powatec Expansion tool	Weidmann	A. van Langen	B. v.d. Bulk	LOW
V7	Breaking tool	_	D. van Woerkom	E. Straver	LOW
V8	LN2 SEM (set van 2)	_	H. Miro	B. van Asten	MEDIUM
V9	LN2 vulstation	_	B. van Asten	C. de Boer	MEDIUM
V10	LN2 Estrellas	_	B. van Asten	C. de Boer	MEDIUM
V11	LN2 MBE	_	B. van Asten	C. de Boer	MEDIUM
V12	LN2 Plassys	_	B. van Asten	C. de Boer	MEDIUM
V13	LN2 AMS Cryo	_	B. van Asten	C. de Boer	MEDIUM
V14	UV/Ozone Cleaner	Bioforce	E. Straver	B. v.d. Bulk	LOW
V15	Clean-up Station	KN Lab	L. Schriek	C. de Boer	LOW